

# Some Implications On Logic Synthesis From The Coming Semiconductor Technologies

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# Agenda

#### ⇒ Opening Remarks

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#### **Opening Remarks**

L. Trevillyan, "An Overview of Logic Synthesis Systems", DAC 1987, Miami, FL

"Although synthesis is not primarily concerned with physical design, some consideration of physical design issues is needed when performing logic design. Even if a synthesized implementation has met all of its logic-level constraints, it still is not a usable design unless it can be placed and wired, and, furthermore, it still satisfies the timing requirements after physical design has been performed." **Some Implications On Logic Synthesis** *"In the Beginning..."* 

> Intrinsic delay + load (#) Interconnect RC was not a concern Timing  $\infty$  # of stages Standard cells libraries included a "delay" element to correct imbalances Area was the real concern Logic minimization was king

# **Some Implications On Logic Synthesis : Planar CMOS** $W \Leftrightarrow Area vs. Timing, T_{OX} \Leftrightarrow Timing vs. Power (Leakage)$



Over time, standard cells libraries have moved from few hundreds to a few thousand elements

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32 Nanometer NMOS high-k metal gate; Source: C.-H. Jan, et al, Intel, IEDM 2010

#### Some Implications On Logic Synthesis : Planar CMOS

Today Libraries Contain Thousand of Elements Many Variants with the Same Footprint (Area) but Different Performance/Power



Source: Synopsys Research, 2016



#### **Some Implications On Logic Synthesis : FinFET** *Quantization of W to Begin with; Eventually 1-Fin; \*Heat\**



Standard cells are "stripped naked" Heavy burden on physical synthesis Utilization declines



22 Nanometer FinFET; Source: K. Mistry, Intel Technology & Manufacturing Day, 2017

#### **Some Implications On Logic Synthesis : Interconnect RC** *Up to 3 Orders of Magnitude Variation Across the Stack*



Resistance ratio across the stack goes above 1,000X AND different masks/patterns for the same layer show different R profiles

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14 Nanometers; Source: Chipworks, 2014

#### **Some Implications On Logic Synthesis : GAA** *Eventually 1-Nano-Wire/Sheet/Slab ? \*Heat\**



Theoretically, one could stack a different number of devices to implement faster/stronger standard cells without impacting area, but...

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#### **Some Implications On Logic Synthesis : Monolithic 3D** *Routing Only at the Top (BEOL); MEOL Under-Utilized; \*Heat\**



Each tier is made of FEOL + MEOL connected by inter-tier via (same pitch as contact, but highly resistive) **One BEOL at the top** There may be 2 × n tiers

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Source: P. Batude, et al., LETI, VLSI 2011

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# **Opening Remarks**

Logic Synthesis doesn't live alone but is intrinsically tied to Physical Synthesis

Over the last 30 years, synthesis went progressively physical, chasing interconnect RC and power Emerging lithography and devices are dramatically increasing the dependence of synthesis on placement, global routing, track assignment, and possibly even further into routing Heat becomes a much earlier concern

#### Agenda

**Opening Remarks** 

Where Do We Stand ? What Lies Ahead ?
EUV Lithography & Non-Planar Devices

Opening Remarks

Where Do We Stand ? What Lies Ahead ?
EUV Lithography & Non-Planar Devices



# Where Do We Stand ? What Lies Ahead ? Lithography & Devices

ArF Immersion			
Mainstream at 7nm	FinFET		
SAQP	Will stay until 3nm	EUV	
TD rules	No clear "heir" yet Silicon nano-sheets and nano-wires top contenders	Mainstream at 5nm LE/LELE for M0/M1 2D rules temporarily back	
		APU, A&M/S	
GPU, CPU, NPU, TPU,		3D-IC (Active SI)	
5.5D-IC (Passive	SI/Substrate)		

# Lithography Implications – ArFi, EUV, Applications Different Objectives Lead to Very Different Outcomes !

	Minimum Metal Pitch	Minimum Contacted Pitch	MMP × MCP	MCP / MMP	Most Advanced Lithography
N10 (HP)	36nm	54nm	1,944nm <sup>2</sup>	1.5X	SAQP
N7	40nm	57nm	2,280nm <sup>2</sup>	1.425X	LELELE
N10 LPE	48nm	64nm	3,072nm <sup>2</sup>	1.333X	LELELE
N7 LP	40nm	56nm	2,240nm <sup>2</sup>	1.4X	LELELE
N7 LPE	36nm	54nm	1,944nm <sup>2</sup>	1.5X	EUV
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## Lithography Implications – ArF Immersion, SAQP From 2D To 1D Rules, No Jogs, Only One Pitch/Width



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24 Nanometer Pitch, ArF Immersion, SAQP; Source: R. Brain et al., Intel, IEDM 2016

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#### Lithography Implications – EUV SE Life Span

Defocus, Asymmetry, and Latitude Narrow the Breadth of Options Higher NA Can Help, at the Price of Higher Magnification ⇒ Smaller Field



Source: RH Kim et al., IMEC, SPIE 2016

## Lithography Implications – EUV SE Life Span Return To 2D Rules May Be Temporary (at 7 Nanometers)



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11 Nanometer M1 Lines @ 5 Nanometers, EUV SE FF vs. HF Image Intensity; J. van Shoot, et al., ASML, EUVL Workshop, Berkeley, CA, 2016

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From 2D to 1D Routing AND Standard Cells No More Jogs, Tip-to-Tip, and Tip-to-Side Rules, Only One Pitch/Width



#### **Design Implementation At ≤ 10 Nanometers** From 2D To 1D Routing AND Standard Cells



Source: M. van den Brink, ASML Investor Day 2014; Synopsys Research, 2017

# Design Implementation At 7 Nanometers (70 Ångstroms)

End-of-Line Rules Violations at High Pin Count Cell Consecutive Placement Areas When Pins Are Near Cell Boundary, Wire End Extend Beyond Boundary



Source: Synopsys Research, 2016

Placement Must Align Near-by Connected Pins Vertically to Allow Direct Connection on M1, and Avoid Connected Pins in Neighboring Rows Being One Track Off



Source: Synopsys Research, 2017

Vertical Pin Alignment-Aware Placement Reduces Routing Congestion



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Source: Synopsys Research, 2017

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Placement Becomes Increasingly Restricted More and More White Space Is Required to Achieve Legality



Source: Synopsys Research, 2017



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#### **Device Implications – FinFET Prolonged Life Span** *Taller/Closer Fins (Height/Pitch) : 34/60 ⇒ 42/42 ⇒ 53/34*





22, 14 & 10 Nanometer FinFET; Source: K. Mistry, Intel Technology & Manufacturing Day, 2017



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#### **Design Implementation At ≤ 10 Nanometers** *Moore's Law Is Fueled by Single Bullet Weapons*



# **Design Implementation At ≤ 10 Nanometers** *Caveat: Standard Cells Shrink, # of Pins Remains the Same*



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Source: IMEC Technology Forum, 2017



A Nanometer... Tic-Tac-Toe: a 4x6 Grid, P&R Must Route 3 Pins, But... There Are Only 4 <u>Simultaneous</u> Legal Access Points (Via Spacing Rule  $\ge 2\sqrt{2}$  Grids)



Source: Synopsys Research, 2016

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A Nanometer... Tic-Tac-Toe: a 4x6 Grid, P&R Must Route 3 Pins, But... There Are Only 4 <u>Simultaneous</u> Legal Access Points (Via Spacing Rule  $\ge 2\sqrt{2}$  Grids)



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Source: Synopsys Research, 2016

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*Pins Density & Accessibility-Aware Placement Addresses/Mitigates Pins Density/Accessibility, and Routing Congestion Issues* 



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Source: Synopsys Research, 2016

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#### **Device Implications – Beyond FinFET (At 3 Nanometers)** [Stacked] Nano-Wires, and Nano-Sheets





Source: K. Mistry, Intel Technology & Manufacturing Day, 2017; IMEC Technology Forum, 2017; IBM, 2017



#### **Process Exploration At 5 Nanometers (50 Ångstroms)**

2-Input NAND 3D Structure, and Current Flows



Source: V. Moroz, Synopsys, ISPD 2016

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#### **IP Exploration At 5 Nanometers**

What If We Rotate The Fins ? 9-Track vs. 6-Track 2-Input NAND Layout Gate Pitch = 48nm, M1 Pitch = 24nm, Fins Pitch = 48nm



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# **Temperature Distribution**

How Do We Avoid "Hot Spots"? And how about New Structures?



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**Opening Remarks** 

# Where Do We Stand ? What Lies Ahead ? EUV Lithography & Non-Planar Devices Heterogeneous nD Integration

**Opening Remarks** 

Where Do We Stand ? What Lies Ahead ?
EUV Lithography & Non-Planar Devices
Heterogeneous nD Integration

Kazimir Malevich, Two Dimensional Self-Portraits, 1915



# Where Do We Stand ? What Lies Ahead ? Heterogeneous nD Integration

ArF Immersion			
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1D rules	No clear "heir" yet Silicon nano-sheets and nano-wires top contenders	Mainstream at 5nm LE/LELE for M0/M1 2D rules temporarily back	
		APU, A&M/S	
GPU, CPU, NPU, TPU,		3D-IC (Active SI)	
5.5D-IC (Passive	SI/Substrate)		
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# Integration Implications – Beyond The Die Multiple Die/Stacks Onto Multiple Silicon Interposers



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Source: Synopsys Research, 2017



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## Integration Implications – 5.5D-IC Multiple Die/Stacks Onto Multiple Silicon Interposers



© 2017 Synopsys, Inc. 42 "Pascal" 5.5D-IC (3D + 2.5D) Integration; Source: L. Nyland, et al., NVIDIA, GPU Technology Conference 2016

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# Typical 5.5D-IC (3D + 2.5D) HBM-Based Application

GPU Die (21B Transistors @ 12 Nanometers) + 4 HBM2 Stacks (4 × 4GB) Onto Two ? Three ? Or Four ? Silicon Interposer Die Stitched Together

 $GPU = 815 \text{ mm}^2$ 

silicon Interposer(s) = 1,400 mm<sup>2</sup>

"Volta" 5.5D-IC (3D + 2.5D) Integration; Source: J.-H. Huang, et al., NVIDIA, GPU Technology Conference 2017

Integration Implications – 3D vs. Monolithic 3D Coarse vs. Fine Grain, Die vs. Transistors

We are at the dawn of 3D-IC integration Only "discrete" 3D is ready for the primetime Its impact on synthesis is very limited (partitioning) However, monolithic 3D may be around the corner Increasingly complex logic functions/IP could be vertically implemented, in different variants The impact on synthesis may be profound

#### Integration Implications – Monolithic 3D Multiple Tiers Stacked One on Top of Another



Source: P. Batude, et al., LETI, VLSI 2011

#### Some Implications On Logic Synthesis : Monolithic 3D Placement Trivial for Simple Gates, May Get Awfully Complex



Source: G. Cibrario, et al., LETI, 3DIC 2016

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Where Do We Stand ? What Lies Ahead ? EUV Lithography & Non-Planar Devices Heterogeneous nD Integration

Closing Remarks

Giacomo Balla, Futuro, 1923, Private Collection

#### **Closing Remarks**

A lot of the "implications" of the coming semiconductor technologies have a profound impact on synthesis Sheer complexity remains the #1 challenge 1T transistors at 3nm (30Å) translate into up to 100B placeable instances The # of polygons & (L)RC values may exceed  $1P = 10^{15} = 50$  bits

#### **Closing Remarks**

Transistors shrink much faster (30% linear, 50% area) than interconnect (20%) The # of pins/gate remains the same, accessibility/routability is the key problem Synthesis is mostly physical (as opposed to logic) 3D integration will bring challenges beyond the die

#### **Closing Remarks**

At about 2 nanometers CMOS lifespan may, finally, come to an end The quest for a general purpose replacement is still on-going Super-conducting electronics is an emerging candidate, and may be a solid foundation for quantum computing It poses significant challenges to synthesis

# **Some Implications On Logic Synthesis : JJ-Based SCE** *Super-Conducting Electronics & Quantum Computing*



4 °K Required Reversible logic only 10,000X larger than CMOS 1,000X faster than CMOS 1,000X lower power ZERO interconnect R



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